ABSTRACT

A device for the production of microwave plasmas with a microwave generator 1 and its coupling system to a waveguide resonator 5 which encloses a plasma chamber 7 is proposed, the short side of the cross-section of the resonator 5 lying parallel, facing the z axis, in the common wall with the chamber 7, and the microwave power being coupled from the resonator 5 into the chamber 7 via coupling points 6 in this short cross-sectional side. The coupling points are preferably formed as azimuthal slot couplers in the common wall of 5 and 7. The reference numbers relate to
Figure 1.